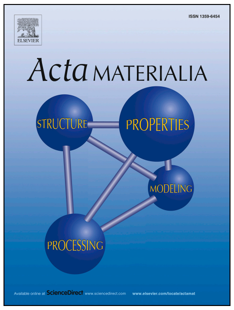
Accepted Manuscript



Tuning the microstructure and mechanical properties of magnetron sputtered Cu-Cr thin films: The optimal Cr addition

X.G. Li, L.F. Cao, J.Y. Zhang, J. Li, J.T. Zhao, X.B. Feng, Y.Q. Wang, K. Wu, P. Zhang, G. Liu, J. Sun

PII: S1359-6454(18)30242-8

DOI: 10.1016/j.actamat.2018.03.044

Reference: AM 14464

To appear in: *Acta Materialia*

Received Date: 4 September 2017

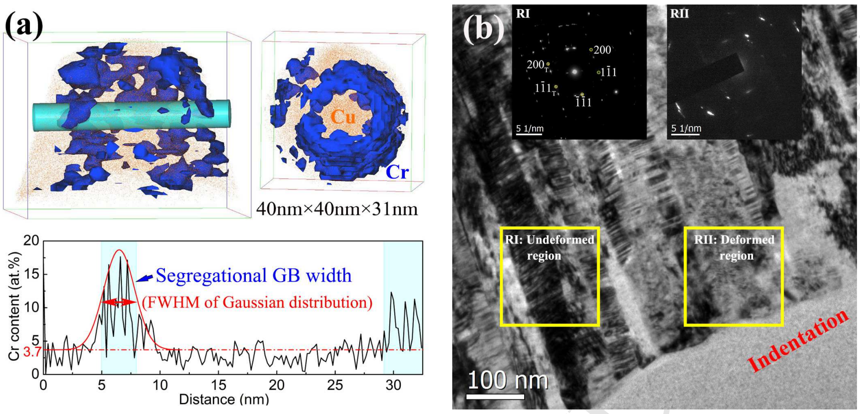
Revised Date: 20 March 2018

Accepted Date: 21 March 2018

Please cite this article as: X.G. Li, L.F. Cao, J.Y. Zhang, J. Li, J.T. Zhao, X.B. Feng, Y.Q. Wang, K. Wu, P. Zhang, G. Liu, J. Sun, Tuning the microstructure and mechanical properties of magnetron sputtered Cu-Cr thin films: The optimal Cr addition, *Acta Materialia* (2018), doi: 10.1016/j.actamat.2018.03.044.

This is a PDF file of an unedited manuscript that has been accepted for publication. As a service to our customers we are providing this early version of the manuscript. The manuscript will undergo copyediting, typesetting, and review of the resulting proof before it is published in its final form. Please note that during the production process errors may be discovered which could affect the content, and all legal disclaimers that apply to the journal pertain.

Graphical abstract



ACCEPTED MANUSCRIPT

Download English Version:

https://daneshyari.com/en/article/7875909

Download Persian Version:

https://daneshyari.com/article/7875909

Daneshyari.com